

whether or not the test object returned to the optical trap or continued to fall.

This determination of the length of an optical trap's influence by this manner assumes that the test object falls through the water in the sample chamber at terminal velocity for the duration of its fall, so that the distance of trap influence can be computed simply by:  $d = V_T t$ , where  $d$  is the trap length (or distance of trap reach),  $V_T$  is the terminal velocity of the test object, and  $t$  is the time interval over which the object is allowed to fall. In order for this methodology to work, it must be established that the test object indeed falls through the water in the sam-

ple chamber at terminal velocity. This answers the question of how far below the trap point an object must be to be drawn into an optical trap in order to select and manipulate material for microscale assembly and characterization.

This methodology would make it possible for optical trapping to be incorporated into the assembly of MEMS (microelectromechanical systems) devices. In particular, adding pieces or connectors to MEMS devices that cannot be positioned via photolithography and vapor or film deposition techniques may be added to a MEMS device via placement by optical traps. In this case, it is impera-

tive to know how far beyond the stable trapping point in the direction of propagation of the beam an object should or must be to be trapped, and also the distance beyond the stable optical trapping point over which the propagating laser beam has no effect.

*This work was done by Susan Y. Wrbanek of Glenn Research Center. Further information is contained in a TSP (see page 1).*

*Inquiries concerning rights for the commercial use of this invention should be addressed to NASA Glenn Research Center, Innovative Partnerships Office, Attn: Steve Fedor, Mail Stop 4-8, 21000 Brookpark Road, Cleveland, Ohio 44135. Refer to LEW-18539-1.*

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This technology leverages the well-defined orbital number of a whispering gallery modulator (WGM) to expand the range of applications for such resonators. This property rigidly connects the phase variation of the field in this mode with the azimuthal angle between the coupling locations.

A WGM with orbital momentum  $L$  has exactly  $L$  instant nodes around the circumference of the WGM resonator supporting such a mode. Therefore, in two locations separated by the arc  $\alpha$ , the phase difference of such a field will be

equal to  $\phi = \alpha L$ . Coupling the field out of such locations, and into a balanced interferometer, once can observe a complete constructive or destructive interference (or have any situation in between) depending on the angle  $\alpha$ . Similarly, a mode  $L + \Delta L$  will pick up the phase  $\phi + \alpha \Delta L$ .

In all applications of a WGM resonator as a modulator, the orbital numbers for the carrier and sidebands are different, and their differences  $\Delta L$  are known (usually, but not necessarily,  $\Delta L = 1$ ). Therefore, the choice of the angle  $\alpha$ , and of the interferometer arms differ-

ence, allows one to control the relative phase between different modes and to perform the conversion, separation, and filtering tasks necessary.

*This work was done by Dmitry Strekalov of Caltech for NASA's Jet Propulsion Laboratory. Further information is contained in a TSP (see page 1).*

*This invention is owned by NASA, and a patent application has been filed. Inquiries concerning nonexclusive or exclusive license for its commercial development should be addressed to the Patent Counsel, NASA Management Office-JPL. Refer to NPO-45730.*

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**This system is applicable in HVAC, methane production plants, and oil refineries.**

*John F. Kennedy Space Center, Florida*

Leak detection and location remain a common problem in NASA and industry, where gas leaks can create hazardous conditions if not quickly detected and corrected. In order to help rectify this problem, this design equips an infrared (IR) camera with the means to make gas leaks of IR-absorbing gases more visible for leak detection and location.

By comparing the output of two IR cameras (or two pictures from the same camera under essentially identical conditions and very closely spaced in time) on a pixel-by-pixel basis, one can cancel out all but the desired varia-

tions that correspond to the IR absorption of the gas of interest. This can be simply done by absorbing the IR lines that correspond to the gas of interest from the radiation received by one of the cameras by the intervention of a filter that removes the particular wavelength of interest from the "reference" picture. This can be done most sensitively with a gas filter (filled with the gas of interest) placed in front of the IR detector array, or (less sensitively) by use of a suitable line filter in the same location.

This arrangement would then be balanced against the unfiltered "measure-

ment" picture, which will have variations from IR absorption from the gas of interest. By suitable processing of the signals from each pixel in the two IR pictures, the user can display only the differences in the signals. Either a difference or a ratio output of the two signals is feasible. From a gas concentration viewpoint, the ratio could be processed to show the column depth of the gas leak. If a variation in the background IR light intensity is present in the field of view, then large changes in the difference signal will occur for the same gas column concentration between the background and the camera. By ratioing the outputs, the